



Aalto University
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Engineering



Near-unity quantum efficiency of broadband black silicon photodiodes with an induced junction

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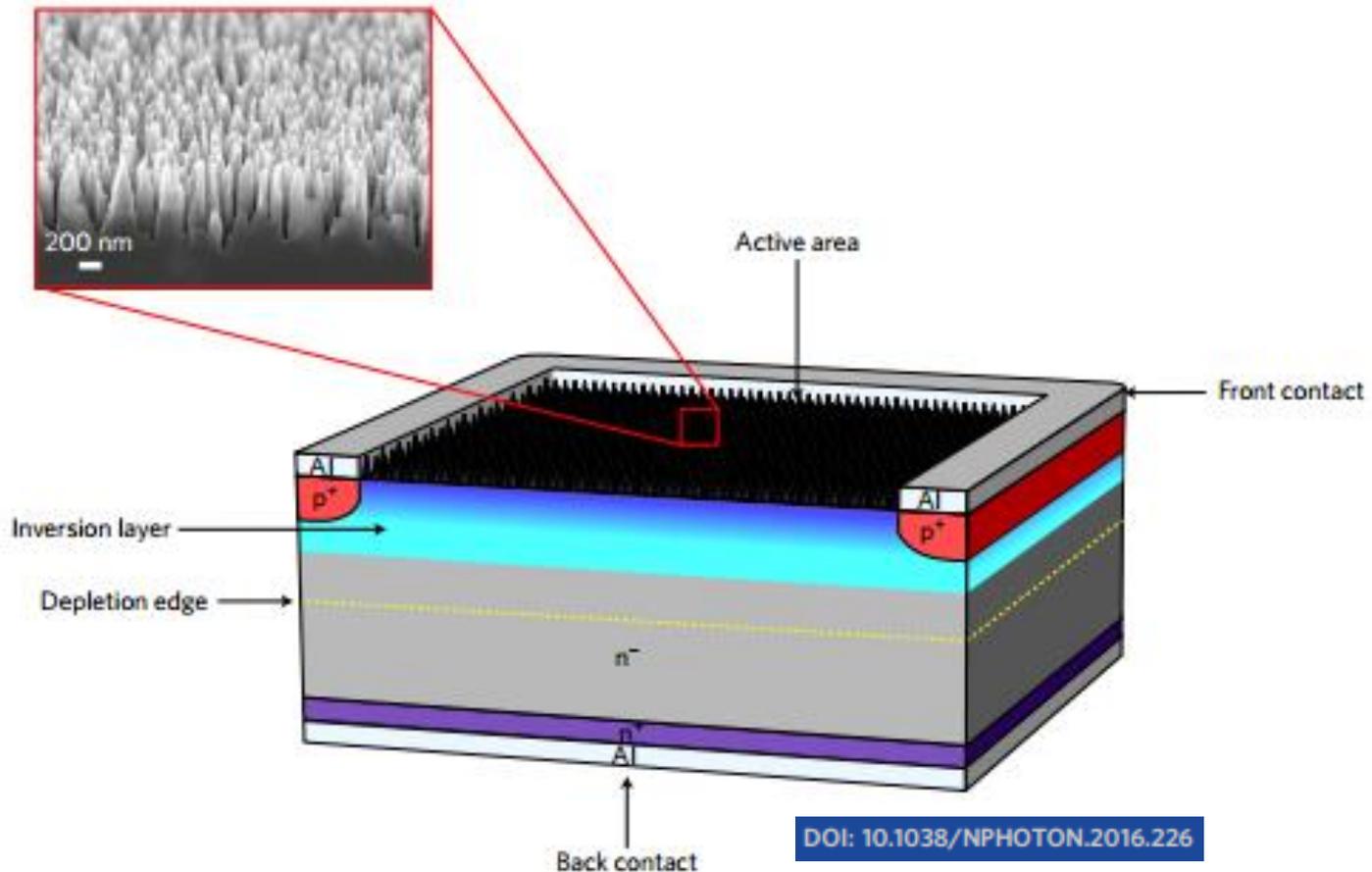
nature
photonics



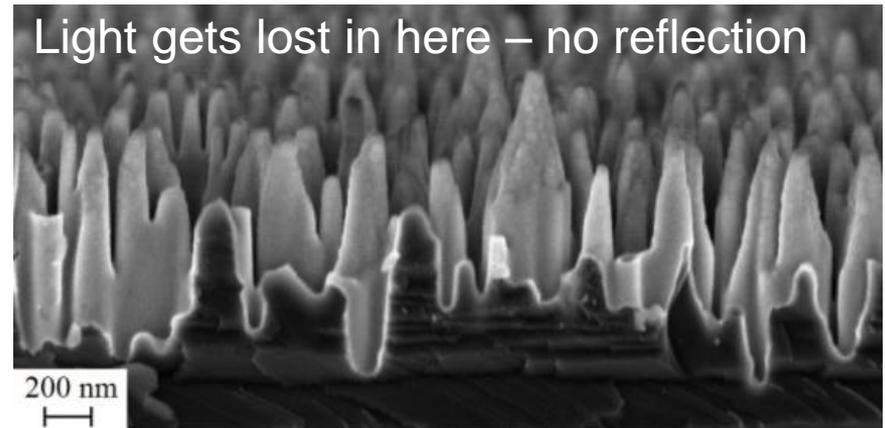
NewStAR

2016-11-23

Black silicon n-type photodiodes with induced junction



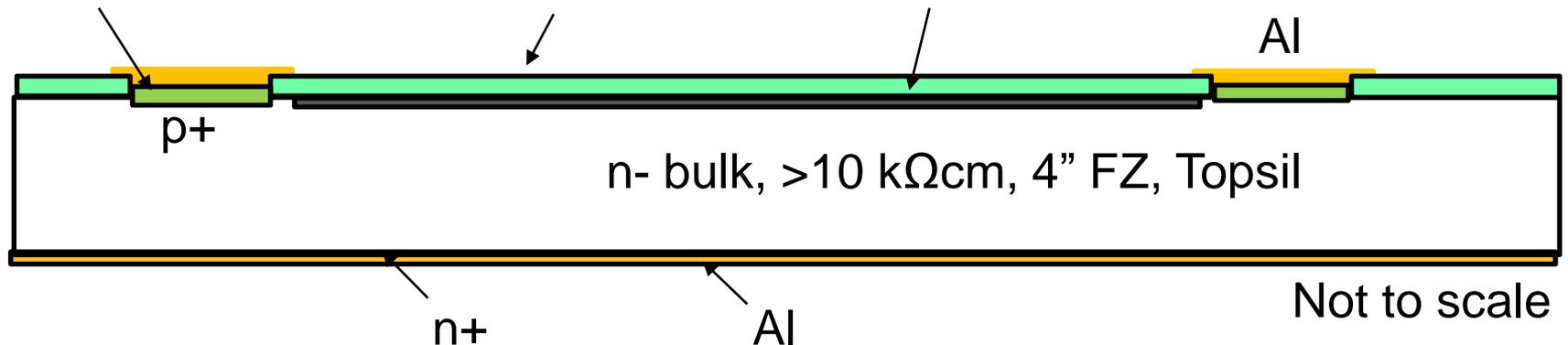
Black silicon n-type photodiodes with induced junction



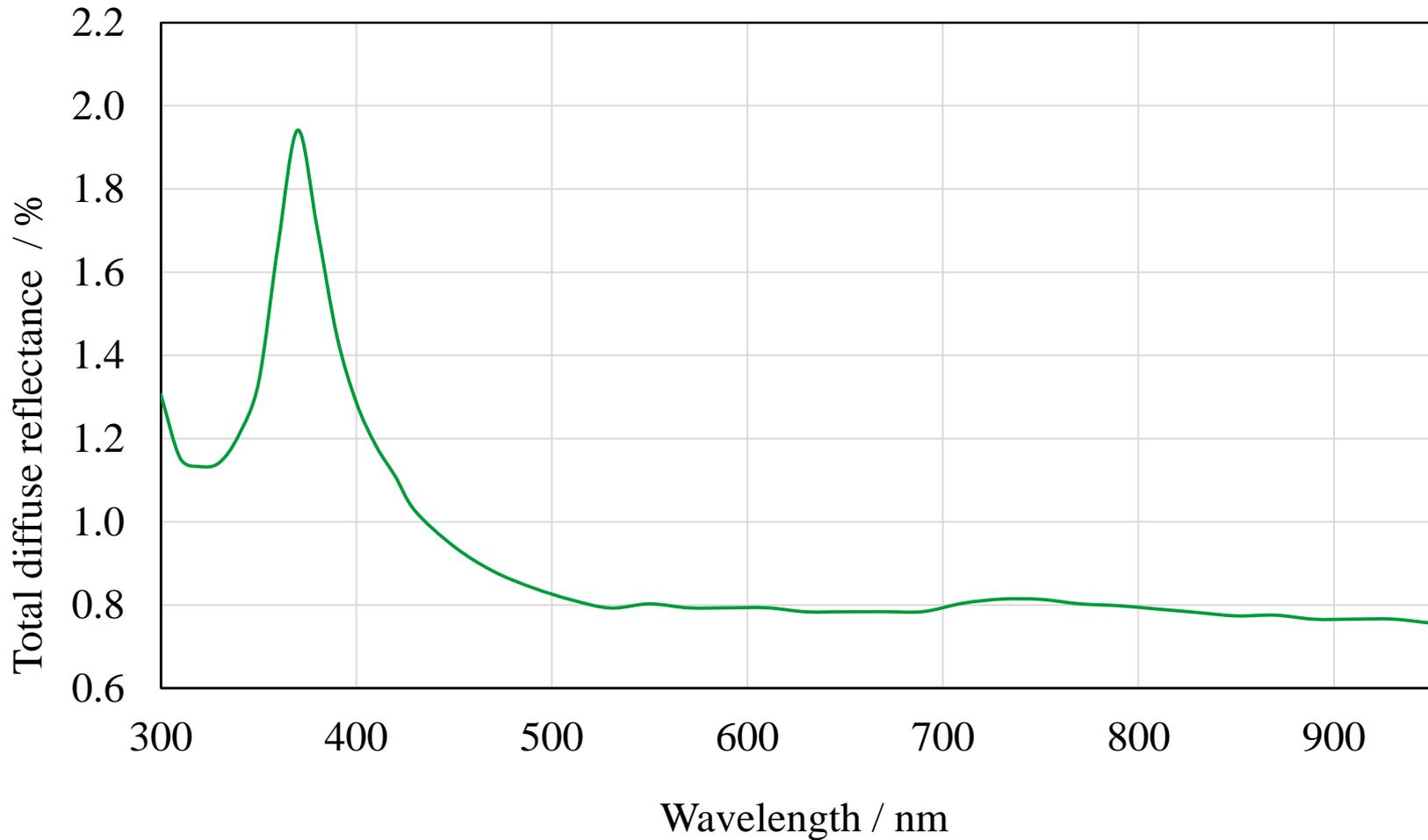
Black Silicon

~20 nm ALD Al_2O_3
Nanostructuring
increases surface
area and charge
~6-fold => deep
inversion

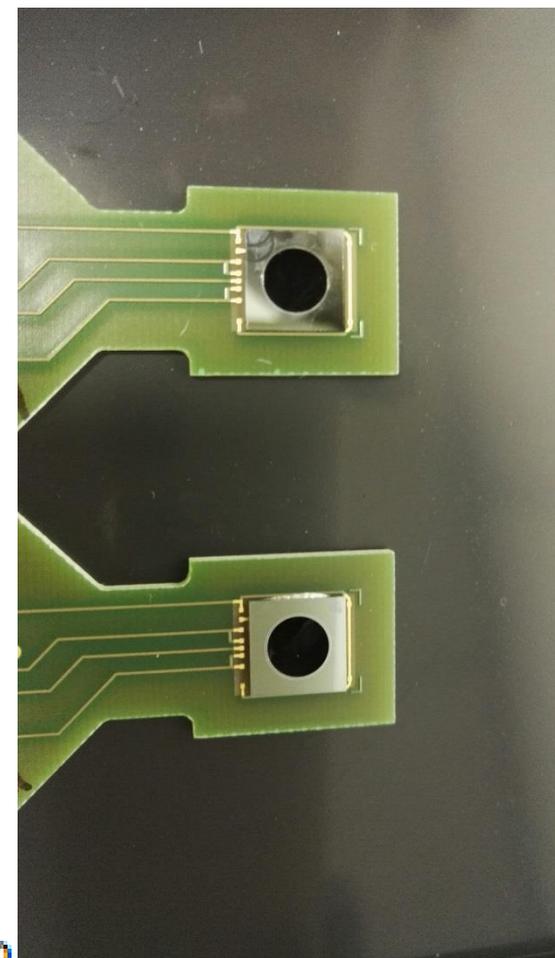
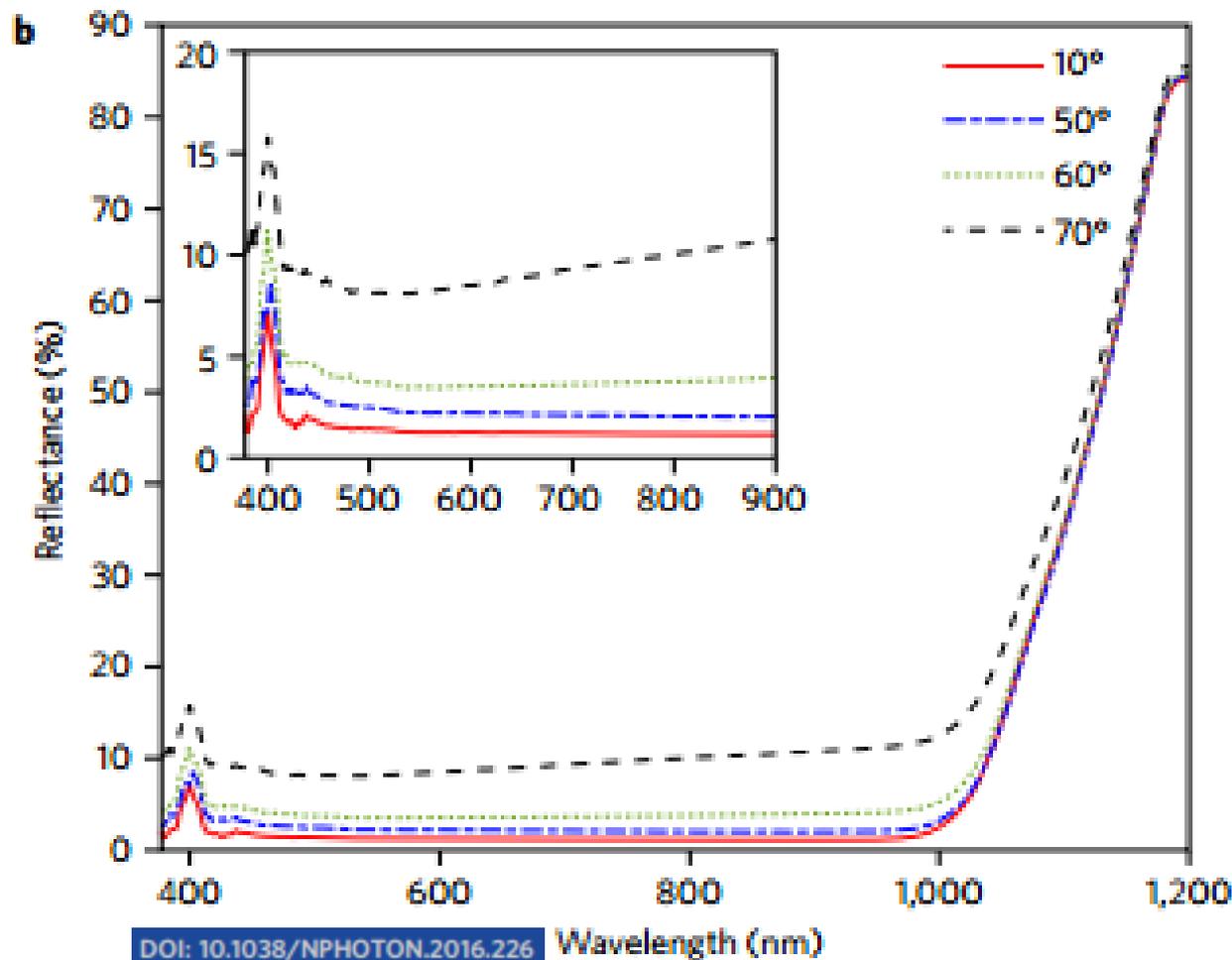
p implantation for
contacts only, no
junction doping



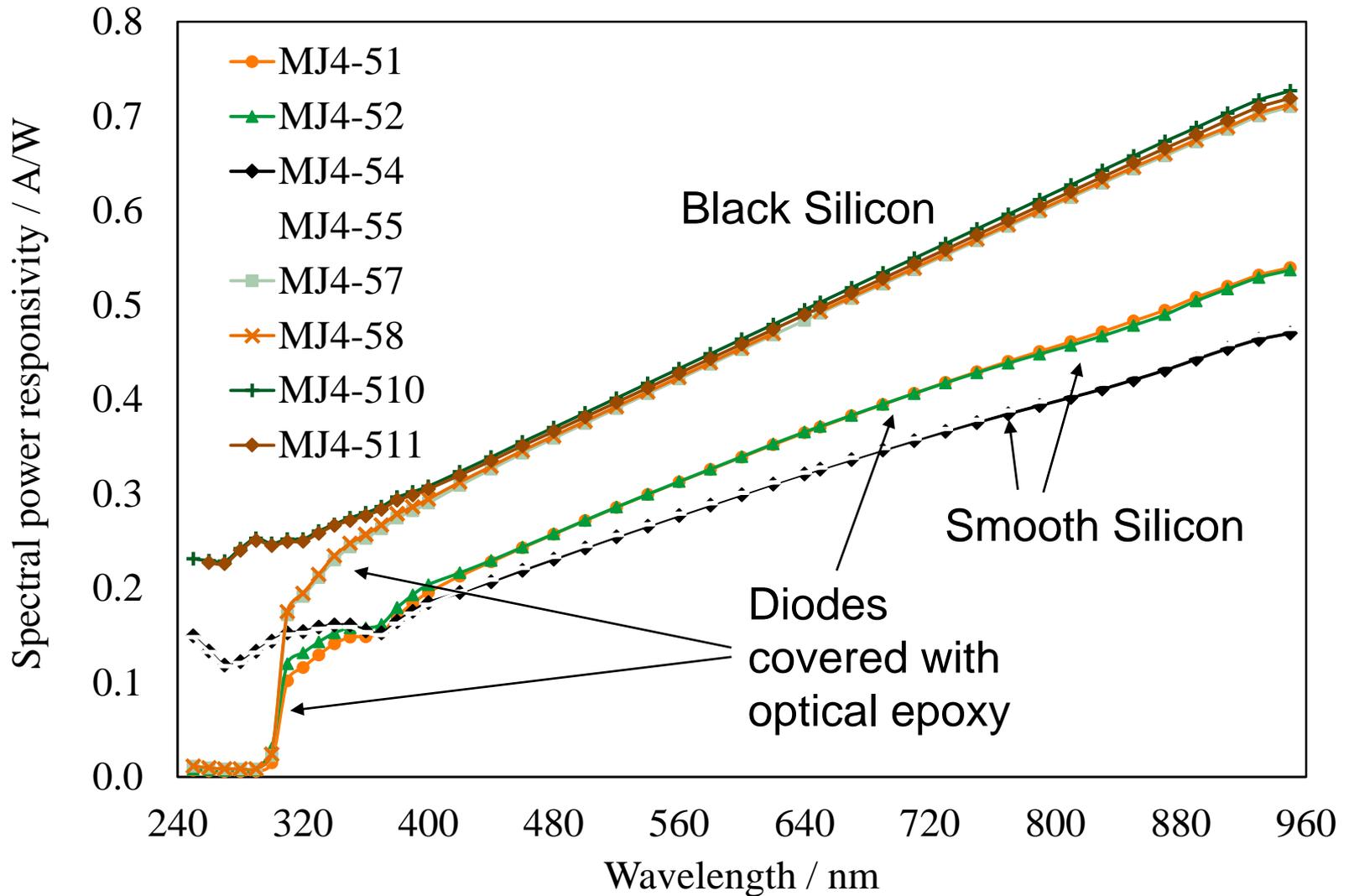
Total reflectance (perpendicular)



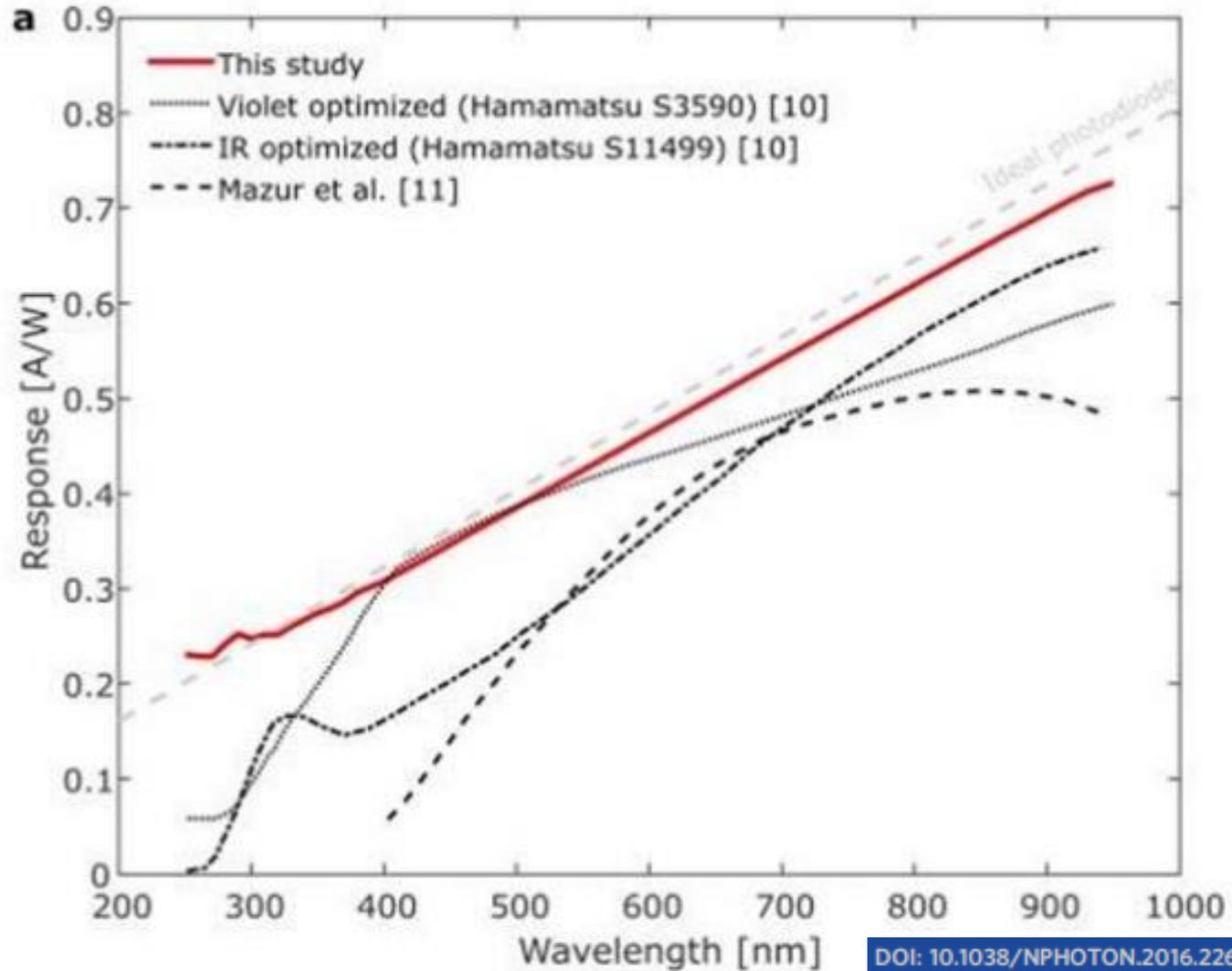
Total reflectance



Spectral Response



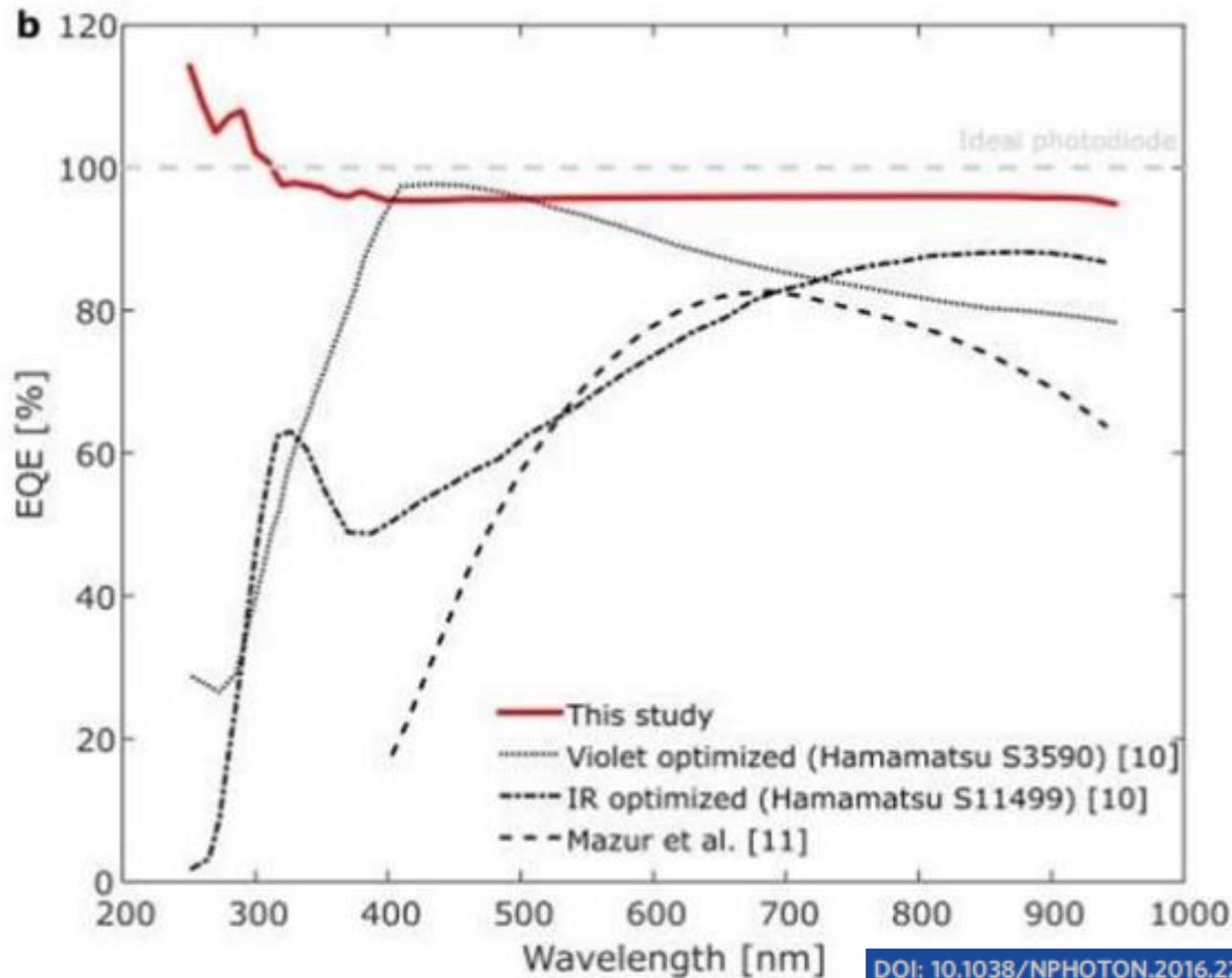
Comparison to some other diodes



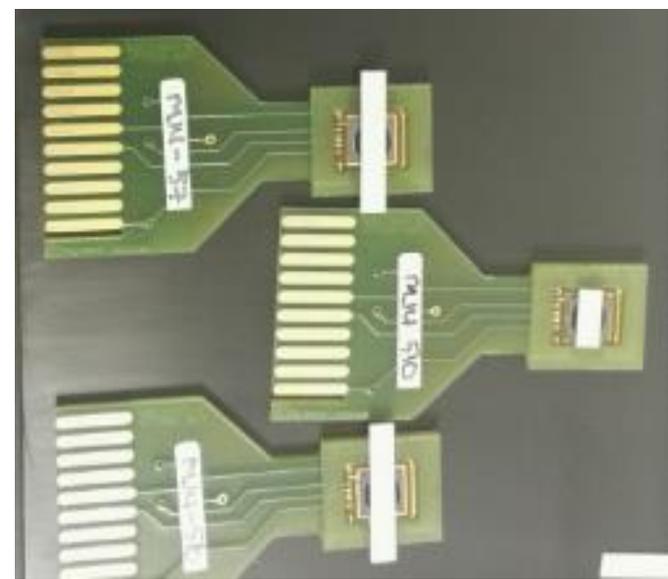
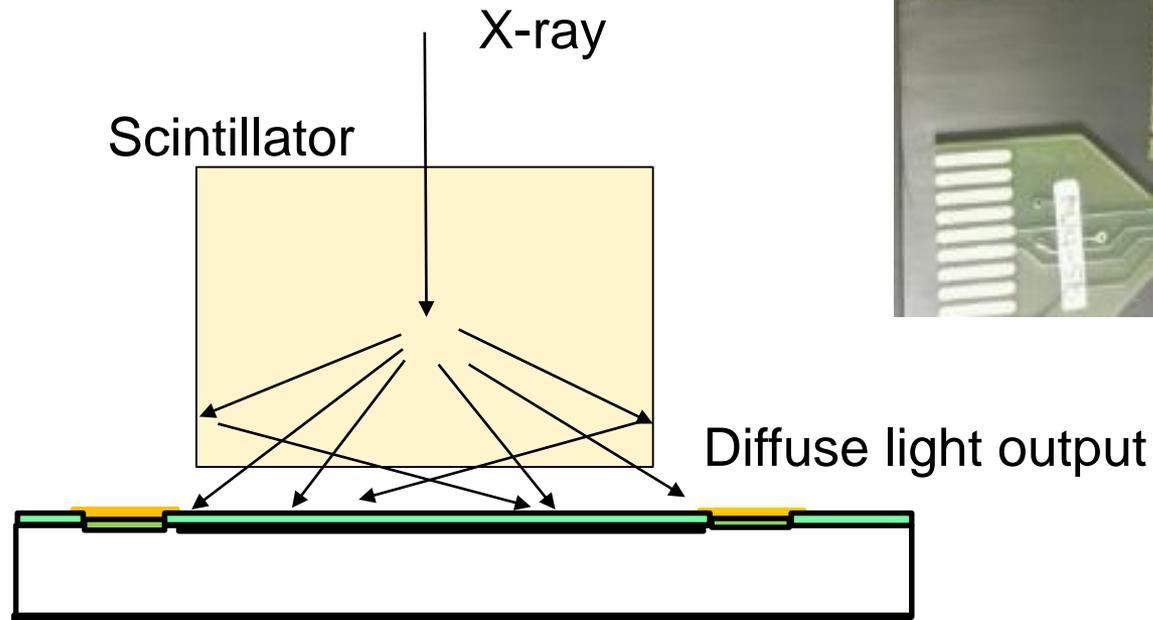
Secondary ionization

- Can occur if photon energy ≥ 3.3 eV ($\lambda \leq 375$ nm)
- With increasing energy probability of impact ionization increases in comparison to phonon excitation
- One photon may create >1 electron-hole pairs
- \rightarrow IQE > 100 %

External Quantum Efficiency >96%



Application example



- Very low reflectance up to 70 degrees incident angle => improved collection of diffuse light.
- Initial X-ray test results comparing to commercial photodiodes indicate >20% improvement.

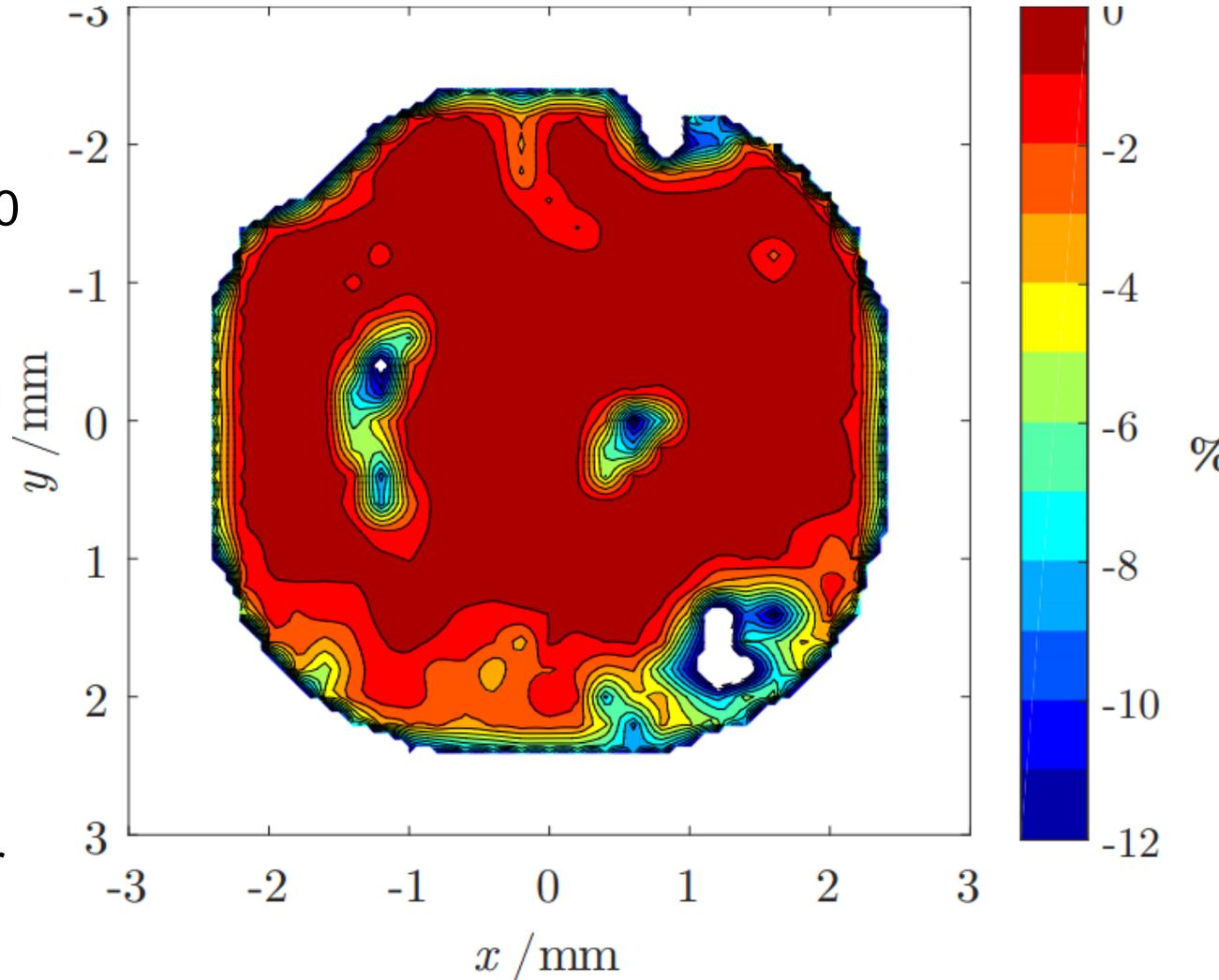
Why not 100% QE

MJ4-510 was scanned with 325nm focused beam with about 200-300 μm diameter

Scratches, dust, vacuum pen mark?

Spectral response was measured with larger beam, bad areas included.

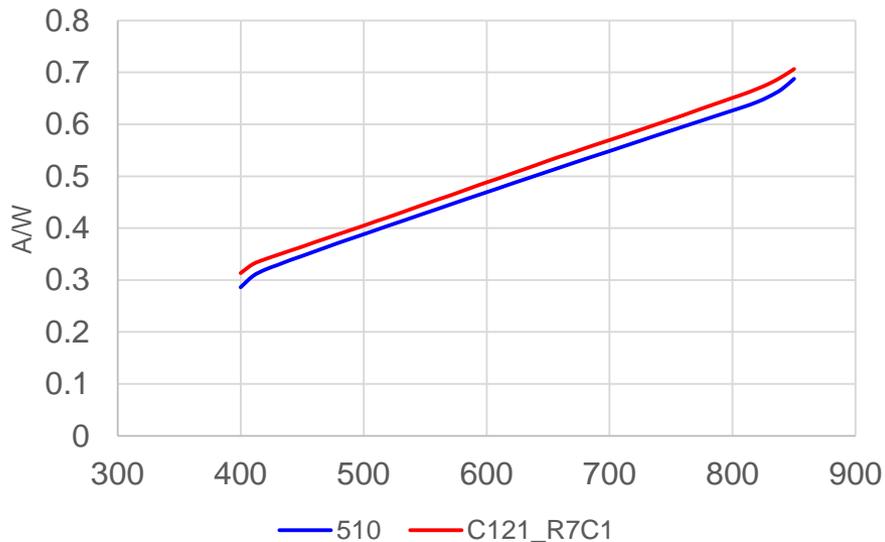
Better handling => better response



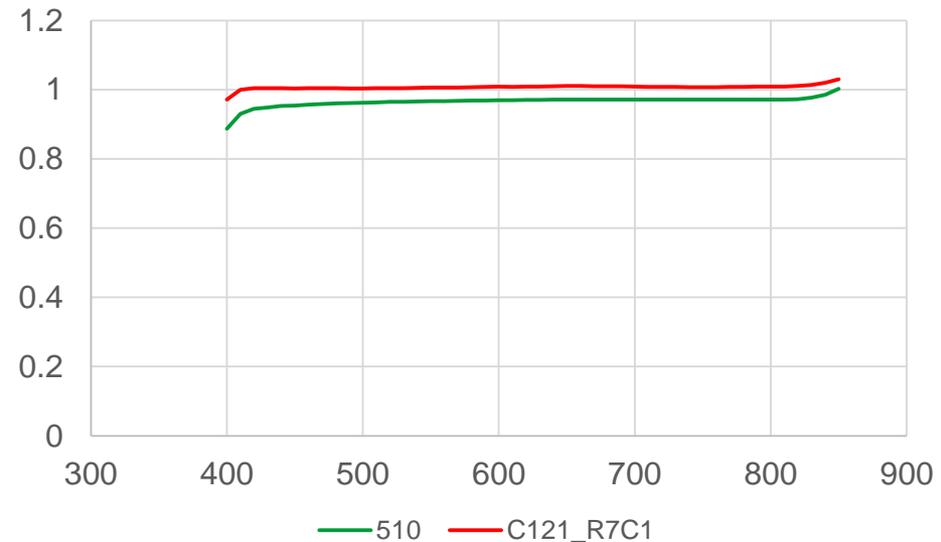
Preliminary results – clear improvement

To be confirmed in calibration laboratory

Response



EQE



Yeah, why not 100%..

Acknowledgements

- Micronova Nanofabrication Centre provided facilities for manufacturing the samples
- Juntunen and Repo were funded through the European Metrology Research Programme (EMRP). The EMRP is jointly funded by the EMRP participating countries within EURAMET and the European Union. Heinonen, Valluru and Vähänissi were funded by the Finnish Funding Agency for Innovation TEKES.
- Mr. Juottonen of Detection Technology, Inc. assembled sample diodes to substrates for measurements
- F. Manoocheri and A. Vaskuri of VTT Technical Research Centre of Finland, Centre for Metrology MIKES measured the response and reflectance
- V. Kübler measured the angle-dependent reflectance measurements